

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
	:	Examiner: J. G. Jelsma
Takako YAMAGUCHI et al.	)	
	:	Group Art Unit: 1795
Application No.: 10/529,891	)	
	:	Confirmation No.: 7802
Completion of Entry into U.S. National	)	
Stage Under 35 U.S.C. § 371(c): July 26, 2005	:	
	)	December 23, 2008
For: EXPOSURE MASK, METHOD OF DESIGNING:	)	
AND MANUFACTURING THE SAME,	)	
EXPOSURE METHOD AND APPARATUS,	:	
PATTERN FORMING METHOD, AND DEVICE)	:	
MANUFACTURING METHOD	:	

**Mail Stop Amendment**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT & SUBMISSION OF SUBSTITUTE SPECIFICATION  
WITH PETITION FOR EXTENSION OF TIME

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Official Action dated September 5, 2008, for one month from December 5, 2008, up to and including January 5, 2008. The statutory fee of \$130.00 for payment of the extension fee is being paid electronically. Please charge any additional fee required for the extension, or credit any overpayment, to Deposit Account 06-1205.

In response to the Official Action dated September 5, 2008, please amend the above-identified application as follows: